



BSI Standards Publication

Semiconductor devices – Non-destructive recognition criteria of defects in silicon carbide homoepitaxial wafer for power devices

Part 2: Test method for defects using optical inspection

National foreword

This British Standard is the UK implementation of IEC 63068-2:2019.

The UK participation in its preparation was entrusted to Technical Committee EPL/47, Semiconductors.

A list of organizations represented on this committee can be obtained on request to its secretary.

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